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U.S. PATENT DOCUMENTS							
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	AL						
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
MDP	AR		IBM Technical Disclosure Bulletin, "Process for Selective Etching of Tantalum Oxide", IBM Corp., Vol. 27,
			No. 12 (May, 1985)
MDP	AS		CHANG, Peng-Heng, et al., "Structures of Tantalum Pentoxide Thin Films Formed by Reactive Sputtering of Ta Metal",
			<u>Thin Film Solids</u> , Vol. 268, No. 1-2, pp. 56-63 (March 15, 1995)
	AT		

EXAMINER <i>Marcel D. Lippman-Peay</i>	DATE CONSIDERED 10/13/2000
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